



ITW

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Hideki SATO

Group Art Unit: 1792

Application No.: 10/594,458

Examiner: L. VINH

Filed: September 26, 2006

Docket No.: 129546

For: METHOD FOR EVALUATING CRYSTAL DEFECTS OF SILICON WAFER

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Pursuant to 37 CFR §1.56, the attention of the Patent and Trademark Office is hereby directed to the reference(s) listed on the attached PTO-1449. Unless otherwise indicated herein, one copy of each reference is attached. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the reference(s) be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

- ☒ 1. This Information Disclosure Statement is being filed more than three months after the U.S. filing date AND after the mailing date of the first Office Action on the merits, but before the mailing date of a Final Rejection, Notice of Allowance or other action that closes prosecution (e.g., Quayle Action).
- ☒ a. I hereby certify that each item of information contained in this Information Disclosure Statement was first cited in any communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of this Information Disclosure Statement. 37 CFR §1.97(e)(1).
- ☒ 2. One or more reference cited herein was cited in a counterpart foreign application. An partial English language version of the foreign Office Action is attached for the Examiner's information. See References 1-7.
- ☒ 3. In accordance with 37 CFR §1.98(a)(2)(ii), copies of any U.S. patents and patent application publications are not attached.
- ☒ 4. An English language Abstract of one or more non-English language reference is attached. See References 3-7.
- ☒ 5. A computer-generated English language translation of one or more Japanese Patent Publication cited herein has been obtained from the website of the Japanese Patent Office ([<http://www.jpo.go.jp>]), and is attached, but has not been reviewed for accuracy. See References 5 and 7.

- ☒ 6. References 1 and 2 correspond to references 4 and 6, respectively.
- ☒ 7. JP-A-11-238773, which is cited in the Japanese Office Action, was previously disclosed in an Information Disclosure Statement filed September 26, 2006.

Respectfully submitted,



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WPB:NAB/kjl

Date: August 20, 2009

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